

PATENT

App. Dkt. No. APPM/003177.D1/CPU/B/PJS

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Wang, et al.

Serial No.: 10/646,405

Confirmation No.: 9508

Filed: August 22, 2003

For: Method and Apparatus For  
Ionized Plasma Deposition

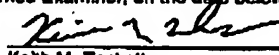
Group Art Unit: 1753

Examiner: Rodney Glenn McDonald

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Commissioner for Patents  
P.O. Box 1450  
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Dear Sir:

CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 CFR 1.8	
I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number indicated by the Examiner, namely, fax number 571-273-8300 to the attention of the named Examiner, on the date below.	
March 10, 2006 Date	 Keith M. Tackett

**RESPONSE TO FINAL OFFICE ACTION DATED JANUARY 10, 2006**

In response to the Final Office Action dated January 10, 2006, having a shortened statutory period for response set to expire on April 10, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/003177.D1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 7 of this paper.

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